



Spin Coating System

UTS series

Spin Coater



UTS-100-008

- Wafer size & throughput : 4 " single wafer / run
- RPM : Max. 8,000
- Vacuum pump : Diaphragm pump(35 l/min)
- System interlock : Process run interlock (Vacuum, Door)
- Program : 10 programs (10 recipe at each program)
- PLC & Touch control

Compact size (table-top) and Low cost system